IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of:

INOUE et al.

Serial Number: 09/473,988

Group Art Unit: 2814

Filed: December 29, 1999

Examiner: T. Doan

SEMICONDUCTOR DEVICE AND METHOD OF MANUFACTURING THE SAME

## <u>AMENDMENT</u>

Director of Patents and Trademarks Washington, D.C. 20231

December 6, 2000

Sir:

For:

In response to the Office Action dated September 6, 2000, please amend the above-identified application as follows:

## IN THE SPECIFICATION:

Please amend the specification as follows:

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Page 4,

line 16, change "increases" to -increase-.

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## IN THE CLAIMS:

Please cancel claim 10 without prejudice or disclaimer.

Please amend claims 1-3 and 7-9 as follows:

A semiconductor device comprising an insulating interlayer formed (Amended) 1. on a conductive film and including [an] first insulating layer of a composition containing SiN, and a second insulating layer formed on said first insulating layer,